



# Monte Carlo Study of Thermal Rectification in Nanostructured Asymmetric Boundaries

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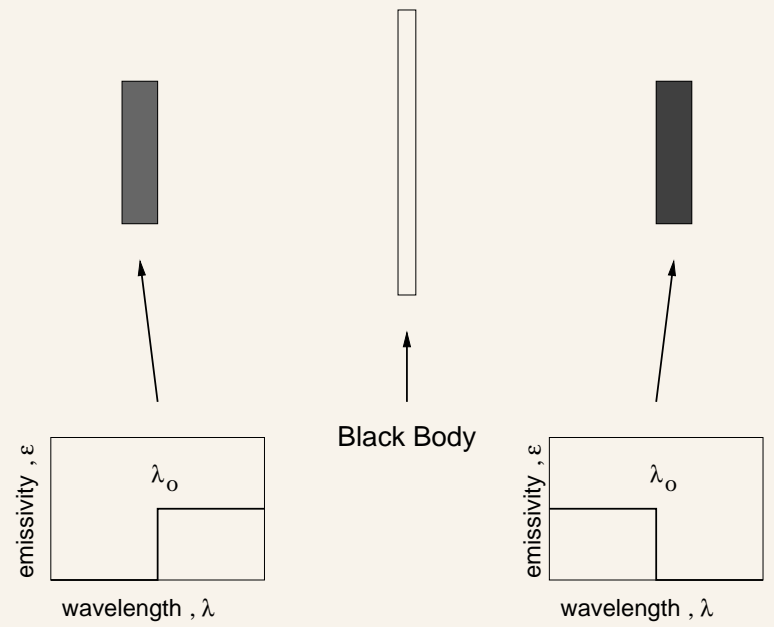
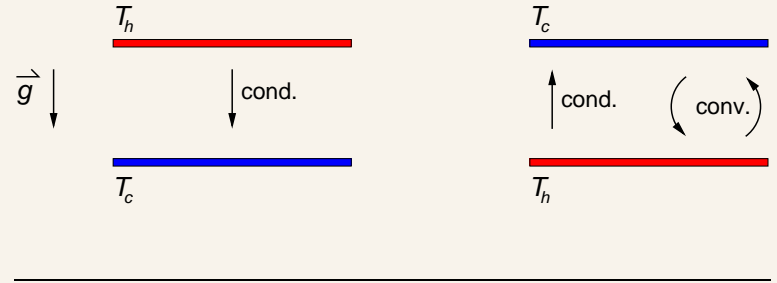
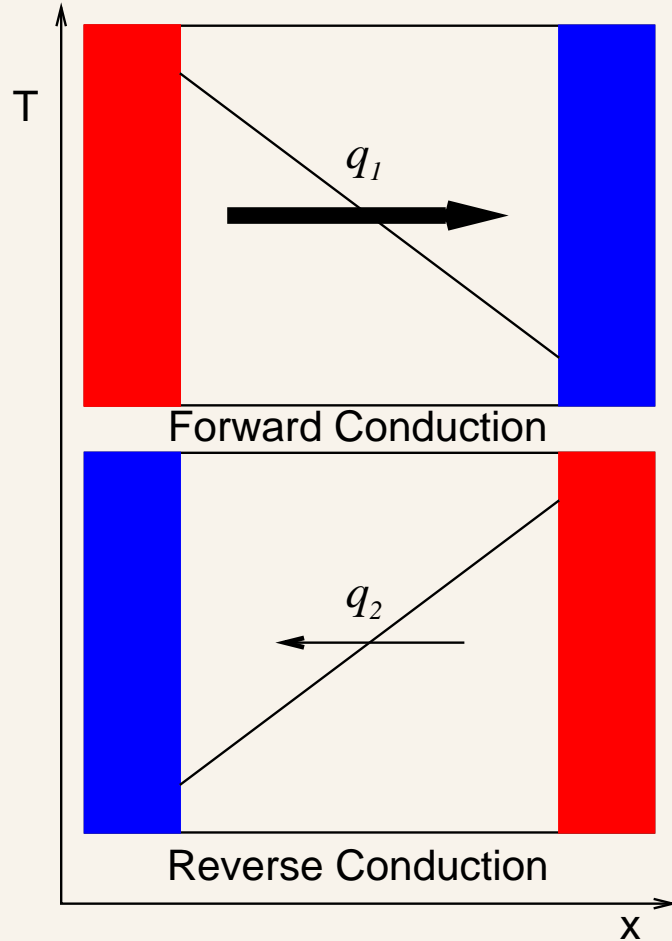
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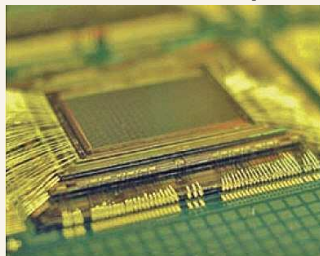
Thermal rectification is a phenomenon where transport through a device is dependent on direction



## Smart Thermal Systems



## Chip Technology



[directindustry.com](http://directindustry.com)



[micropower-global.com](http://micropower-global.com)

## Thermoelectrics



[melcor.com](http://melcor.com)

## Portable Electronics



## Thermal Barrier Coatings



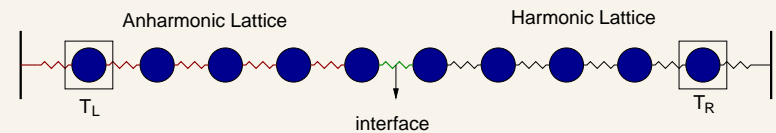
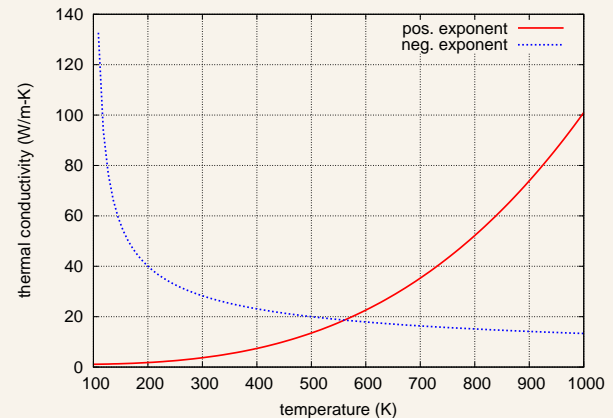
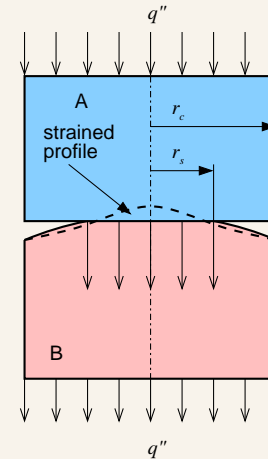
[siemens.com](http://siemens.com)

First reported observation was by Starr in 1936

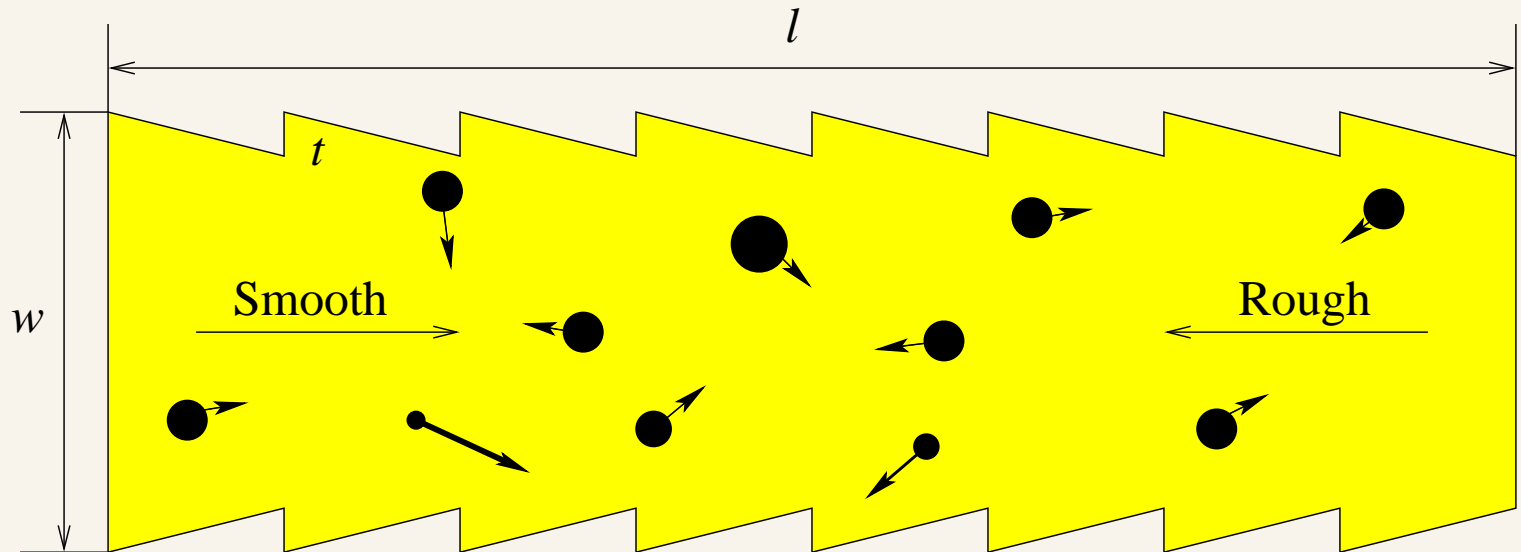
Level of rectification:  $\mathcal{E} = \frac{\kappa^+ - \kappa^-}{\kappa^+ + \kappa^-}$

Investigators	System	Mechanism	$\mathcal{E}$
Starr, 1936	Cu/Cu <sub>2</sub> O	electronic	0.39
Barzelay, 1955	Al/SS	thermal warping	0.67
Rogers, 1961	Al/SS	thermal potential barrier	0.1
Powell et al., 1962	Al/SS	thermal warping	0
Clausing, 1966	SS/Al	thermal strain	0.2
Lewis and Perkins, 1968	Al/SS	thermal warping	0.41
O'Callaghan et al., 1970	varied	thermal warping	0.13
Stevenson et al., 1991	varied	thermal warping	0.21
Chang et al., 2006	CNT and BNNT	non-uniform mass loading	0.034

- Contact resistance change due to thermal expansion
  - Rogers (1961)
  - Clausing (1966)
  - O'Callaghan (1970)
- Temperature dependence of thermal conductivity
  - Sun et al. (2001)
  - Hu et al. (2006)
  - Dames (2009)
- Nonlinear lattice/potential
  - Terraneo et al. (2002)
  - Li et al. (2004)
  - Segal and Nitzan (2005)
  - Casati (2005)



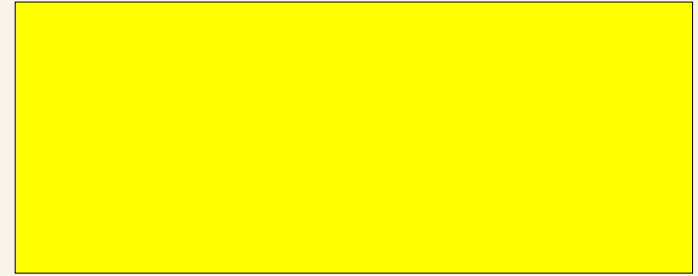
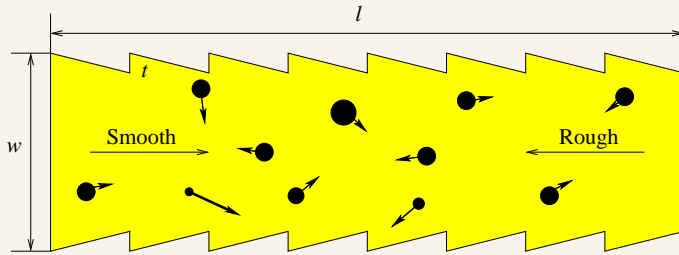
## Simulations using Monte Carlo technique



- Initialization
  - Number of phonons initially prescribed ( $\geq 100,000$ )
  - Randomly distributed throughout the device
  - Polarization and frequency obtained based on initial temperature
  - Momentum calculated from analytic dispersion relation
- Three-phonon scattering is used based on the model and rates from *Holland, Physical Review, 1963*
- Cross sections of  $10 \times 10$  nm to  $1000 \times 1000$  nm and lengths of 10 nm to 1000 nm

$$\begin{aligned} \text{Analytic phonon dispersion} &\Rightarrow \omega(k) = \omega_{max,b} \sqrt{\frac{1-\cos ka}{2}} \\ \text{Max. TA and LA frequencies} &\Rightarrow 1.23 \times 10^{13} \text{ Hz}, 4.5 \times 10^{12} \text{ Hz} \\ \text{3-D Density of States} &\Rightarrow D(k) = \frac{k^2}{2\pi^2 V_g} \\ \text{Phonon group velocity} &\Rightarrow V_g = \nabla_k \omega \\ \text{Bose-Einstein distribution} &\Rightarrow \langle n \rangle = \frac{1}{\exp \frac{\hbar\omega}{k_B T} - 1} \end{aligned}$$

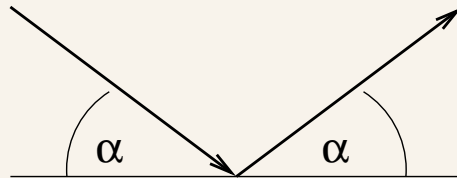
# Direction- and Frequency-Dependent Boundaries



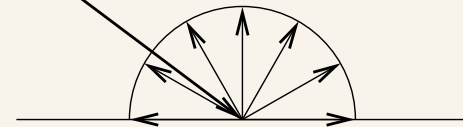
- Boundaries parallel to x-axis have direction and frequency dependence
- If a phonon with negative x-momentum strikes a boundary parallel to the x-axis a parameter,  $p(\omega, \eta)$ , is calculated based on the phonon frequency and characteristic roughness
- If  $p \ll 1$ , the phonon has a high probability of a diffuse reflection

$$p(\omega, \eta) = \exp\left[-\frac{64\pi^5 \eta^2 \omega^2}{V_g^2}\right]$$

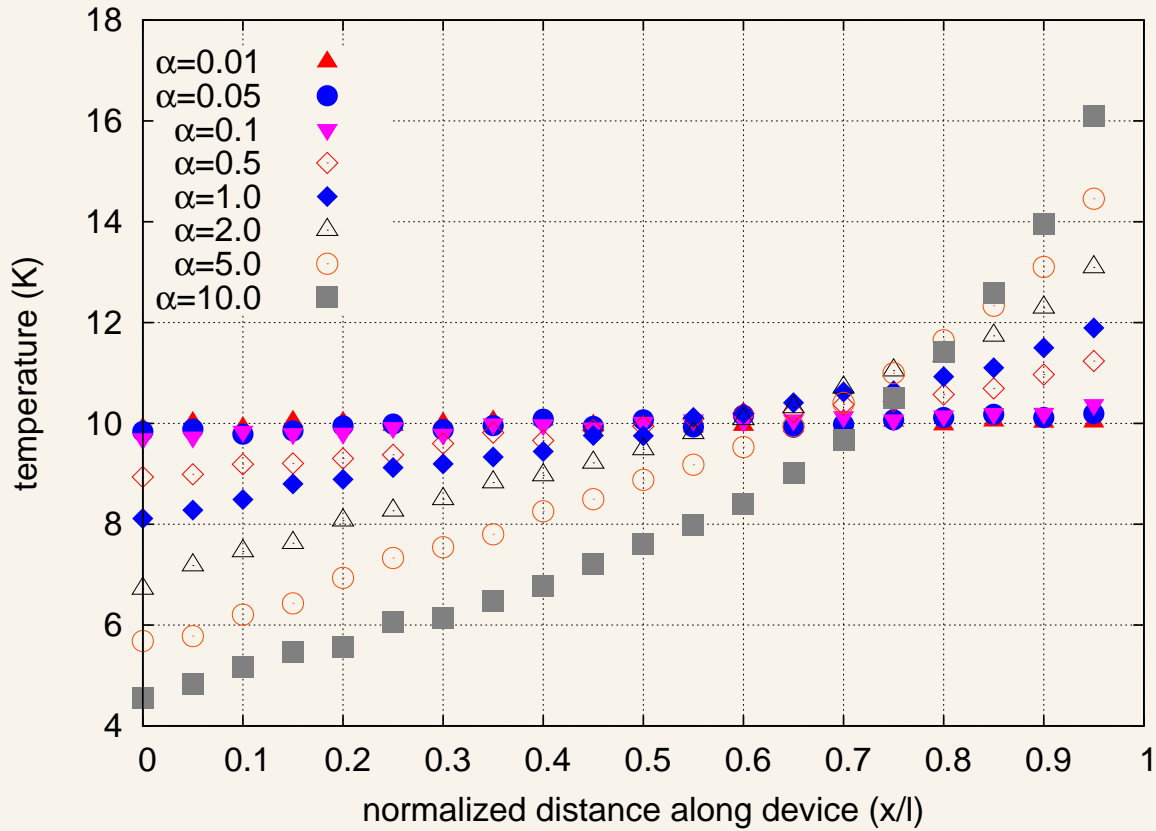
Ziman, *Electrons and Phonons*, 1960



Specular Reflection

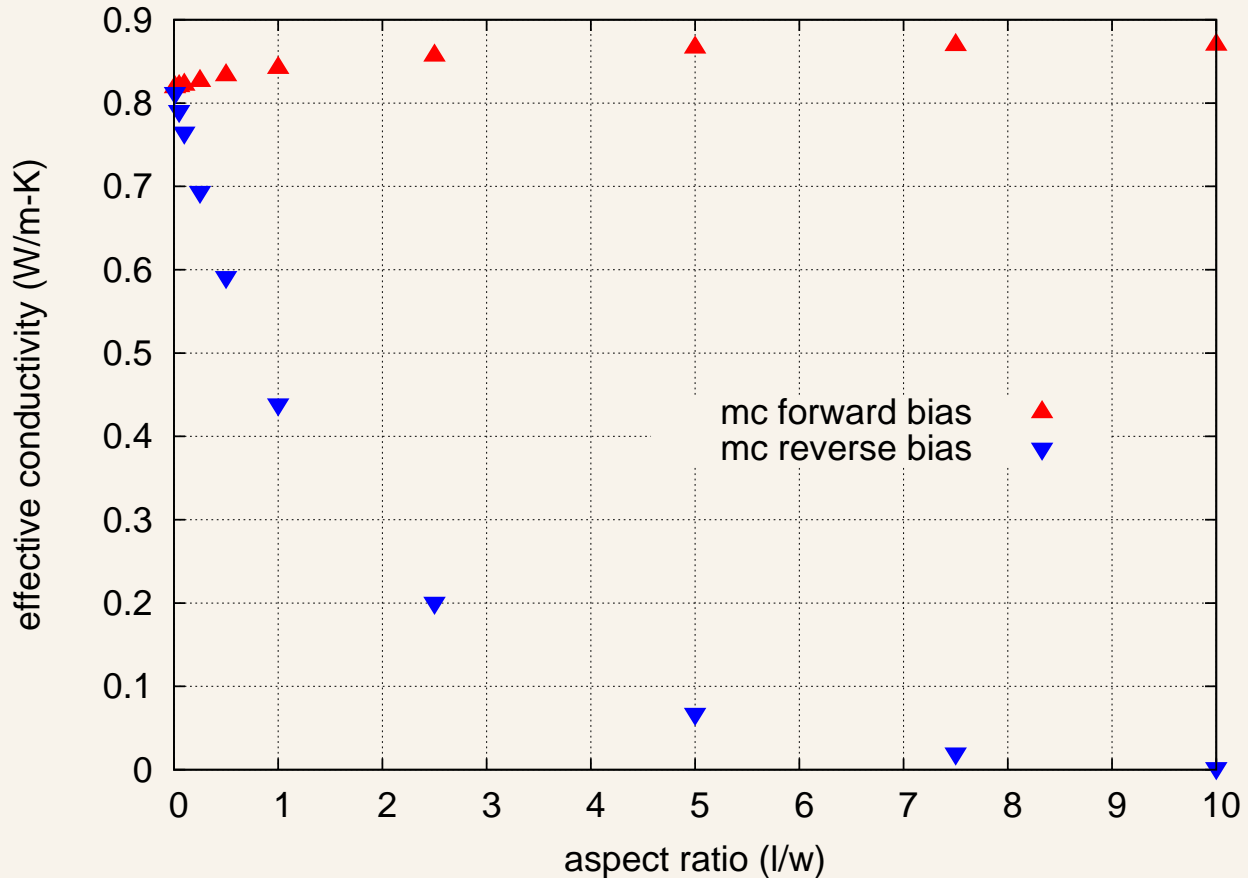


Diffuse Reflection

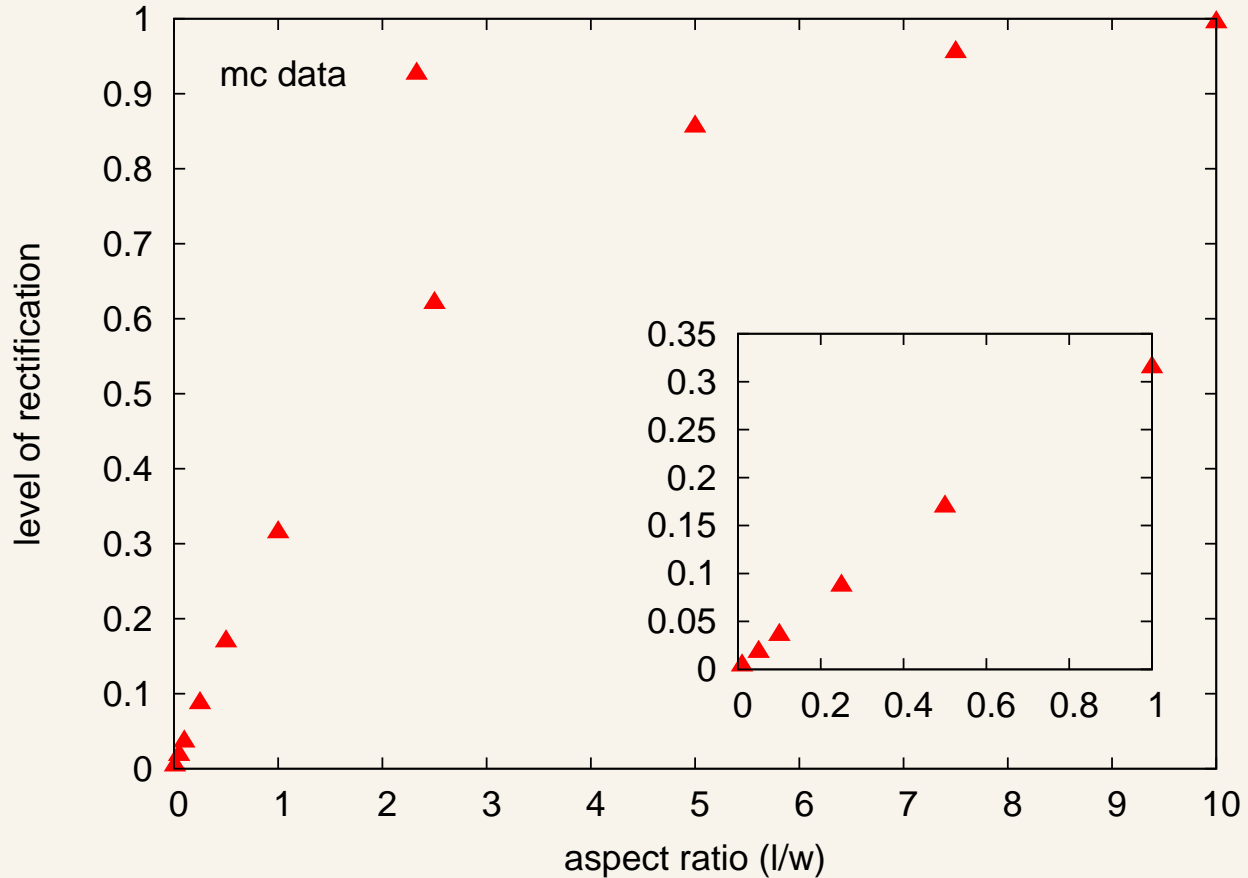


$$\alpha = l/w$$

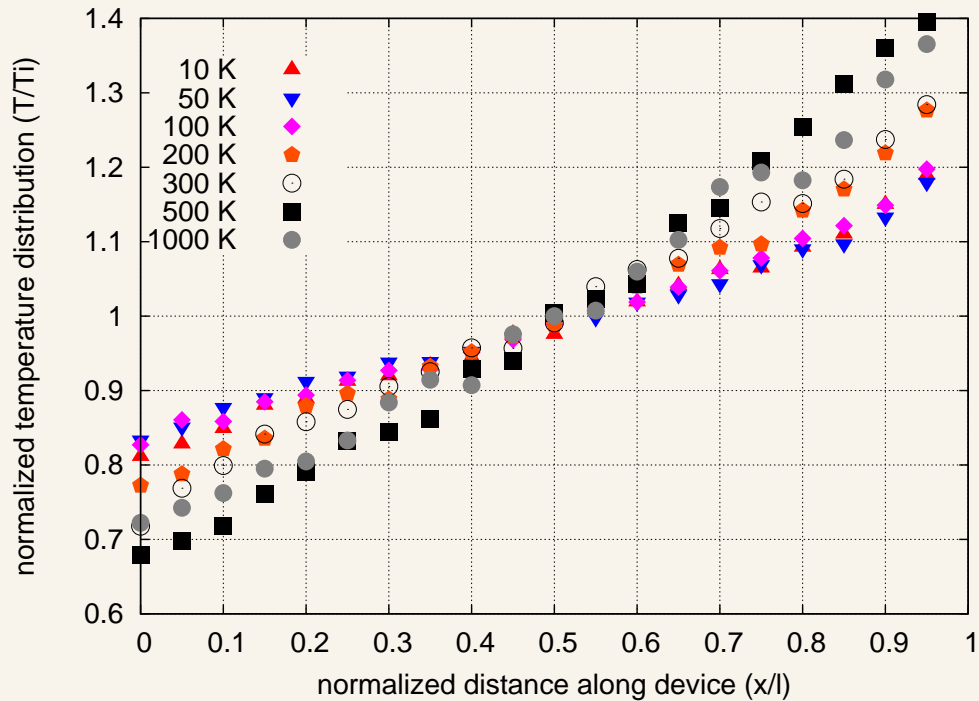
- Boundaries are insulated, so the device is self-biasing.



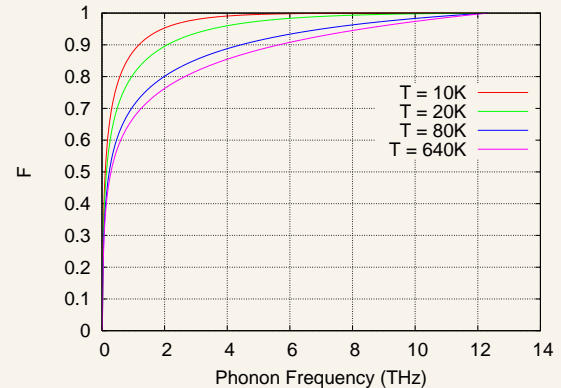
- For a biased device, the amount of transport is calculated so thermal conductivity can be deduced.

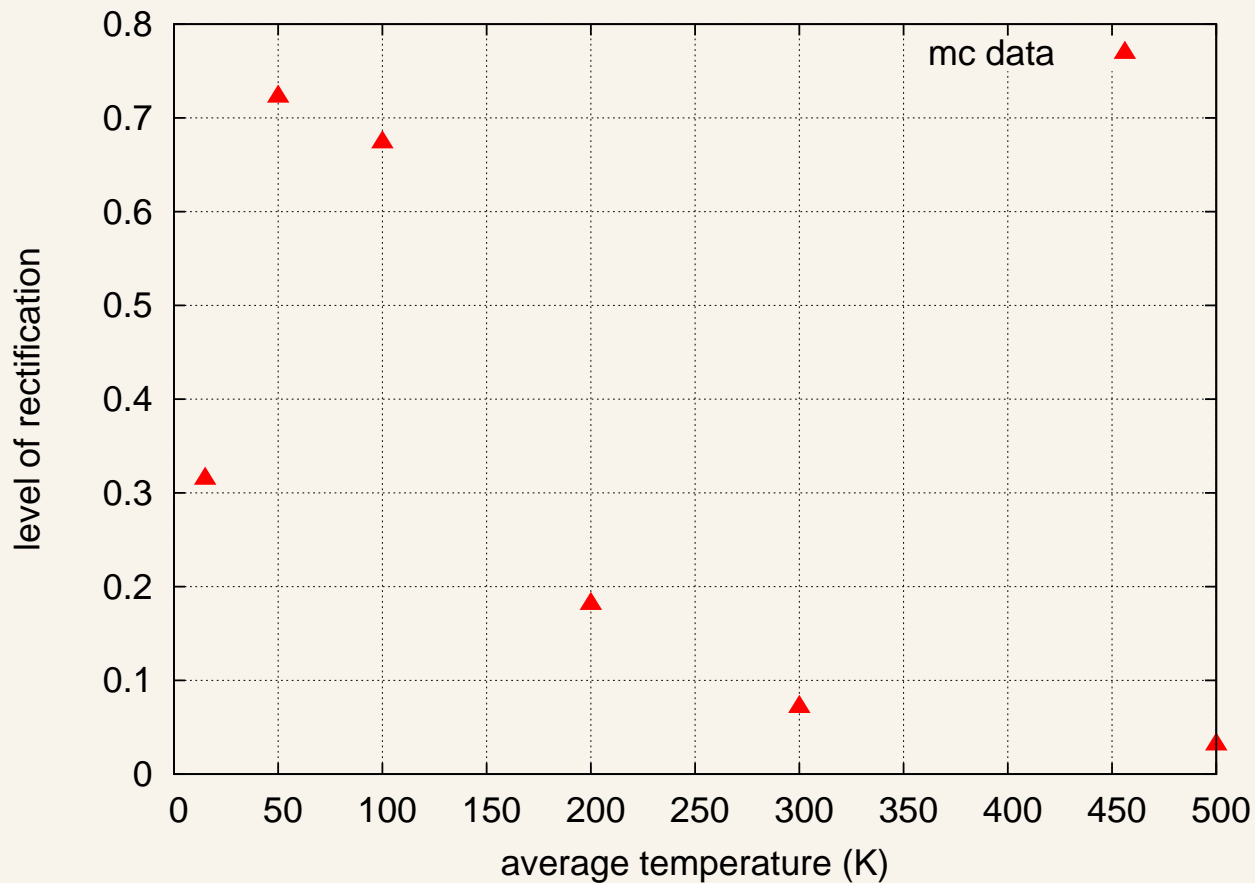


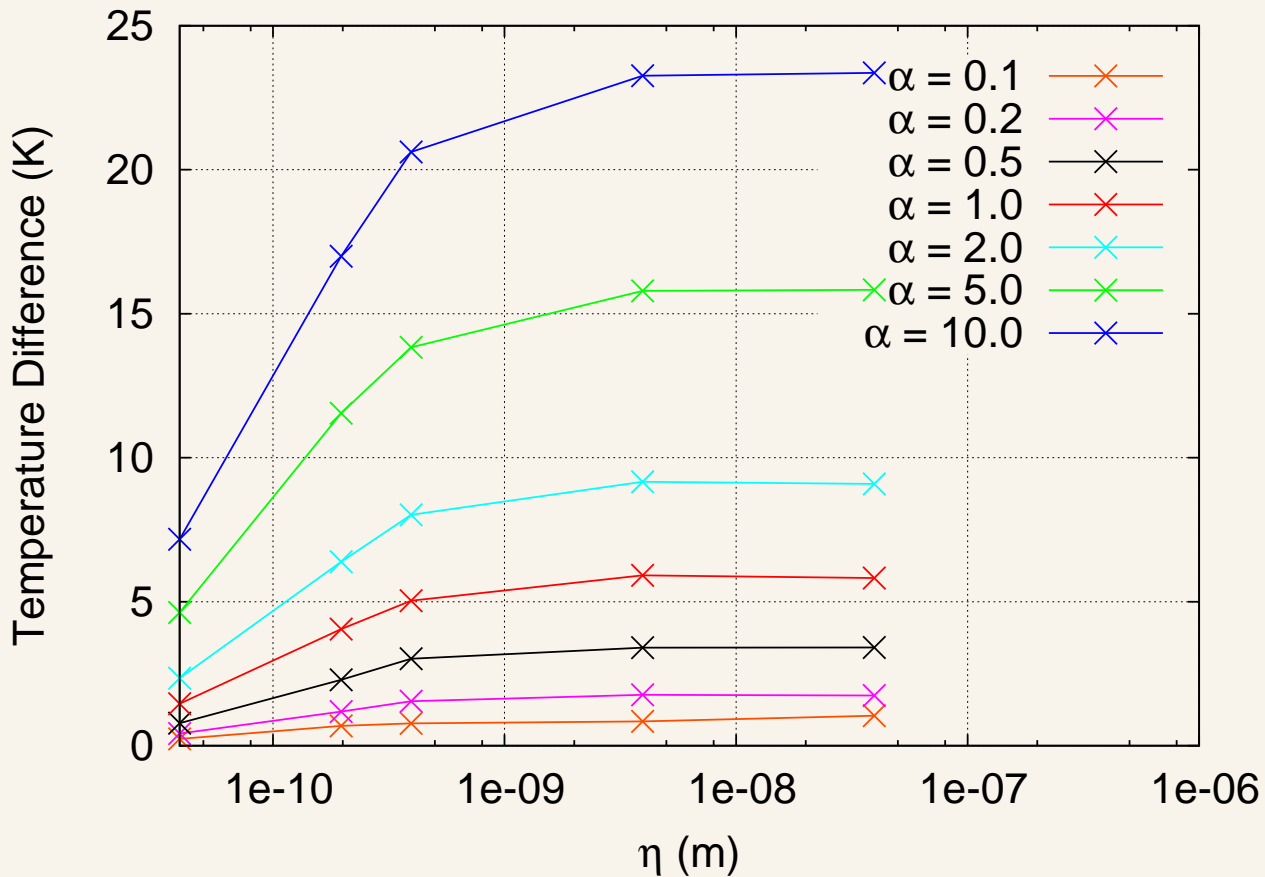
- boundary dominated devices show large amounts of rectification
- $\varepsilon = 1$  means no transport in unfavorable direction



$$F(\omega) = \sum_b \frac{\int_0^\omega \langle n \rangle D(\omega) d\omega}{\int_0^{\omega_{\max,b}} \langle n \rangle D(\omega) d\omega}$$







- Rectification can be increased by
  - large aspect ratio devices
  - selecting a temperature that gives a distribution of phonons, but does not introduce too much scattering
  - designing a roughness that is of the order of the dominant phonon wavelength
- Fabrication is extremely difficult due to boundary requirements

